



PATENT

Atty. Dkt. No. APPM/003177.D1/CPVL/B/PJS

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Wang, et al.

Serial No.: 10/646,405

Confirmation No.: 9508

Filed: August 22, 2003


For: Method and Apparatus for
Ionized Plasma Deposition

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Group Art Unit: 1753

Examiner: Rodney G. McDonald

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on November 22, 2005 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.	
November 22, 2005	
Date	Signature

Dear Sir:

RESPONSE TO OFFICE ACTION DATED JULY 22, 2005

In response to the Office Action dated July 22, 2005, having an extended statutory period for response set to expire on November 22, 2005, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no fees in addition to the enclosed fee transmittal are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/003177/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Specification begin on page 2 of this paper. **Amendments to the Claims** are reflected in the listing of claims which begins on page 3 of this paper. **Remarks** begin on page 8 of this paper.